What is claimed is:

1. A semiconductor factory automation (FA) system, comprising:

at least one processor for driving a program process and providing processor state information, wherein the processor state information includes an availability of a central processing unit, an availability of a disk and a state of the program process related to said processor;

a storing means for storing the processor state information in a real time;

a monitoring means for retrieving the processor state information in said storing means to monitor said processor; and

a displaying means for displaying the processor state information retrieved.

2. The semiconductor FA system as recited in claim 1, wherein said displaying means includes:

a first display space for displaying the availability of the central processing unit related to said processor; and

a second display space for displaying the availability of the disk related to said processor.

3. The semiconductor FA system as recited in claim 2, wherein said displaying means further includes:

a first light emitting device for emitting a light when the disk has failed;

a second light emitting device for emitting the light when the

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program process is in a down state; and

a third light emitting device for emitting the light when a communication between said monitoring means and said processor is disconnected.

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4. The semiconductor FA system as recited in claim 3, wherein said displaying means further includes:

a third display space for displaying identification information of the program process of the down state.

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5. The semiconductor FA system as recited in claim 4, wherein said processor is coupled to Ethernet™ supplied by Xerox Corporation.

6. The semiconductor FA system as recited in claim 5, wherein 15 said at least one processor includes a first processor and a second processor.

7. The semiconductor FA system as recited in claim 6, further comprising:

20 a semiconductor processing means coupled to said first processor for processing a semiconductor wafer cassette containing a predetermined number of semiconductor wafers;

a stocking means coupled to said second processor for stocking the semiconductor wafer cassette; and

25 a transportation means for transporting the semiconductor wafer cassette from said semiconductor processing means to said stocking means or from said stocking means to said semiconductor processing

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means.

8. A method for monitoring at least one server in a semiconductor factory automation (FA) system, comprising the steps of:

a) providing server state information from at least one server to a real-time database, wherein the server state information includes an availability of a central processing unit, an availability of a disk and a state of a program process related to the server;

b) storing the server state information in the real-time database;

c) retrieving the server state information to monitor the server; and

d) displaying the server state information retrieved.

9. The method as recited in claim 8, wherein said step d) includes the steps of:

d1) displaying the availability of the central processing unit related to the server; and

d2) displaying the availability of the disk related to the server.

10. The method as recited in claim 9, wherein said step d) further includes the steps of:

d3) emitting a light when the disk has failed; and

d4) emitting the light when the program process is in a down state.

11. The method as recited in claim 10, wherein said step d) further includes the step of:

d5) displaying identification information of the program 5 process of the down state.